



Evidence of multistage charge collection in Si irradiated detectors operated as monitors of intensive fragmented proton beams

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Motivation

Motivation of semiconductor detector application for monitoring of proton beam loss in LHC machine:

- installation of compact detectors in the vicinity of superconductive magnets, increase in sensitivity of monitoring the particle loss of proton beam, **initiated by CERN BE-BI** (Beam Div., Beam Instrumentation)

The <u>goal</u> of the presented study:

- further analysis of the results of the unique *in situ* irradiation test of Si detectors;
- new findings in detector and radiation physics at low T

Experiment

In situ irradiation tests (the only method of experimental study at 1.9 K)

2012 – *in situ* irradiation test 1 at 1.9K, 6 weeks of operation:

Si p⁺-n-n⁺ detectors; $\rho \sim 10-15 \text{ k}\Omega$, 300 µm; processed in Russia

Irradiation: 23 GeV protons beam fragmented into 400 ms spills

Beam intensity 1.3×10^{11} p/cm² per 400 ms spill (~10¹⁰ p/s on detectors)

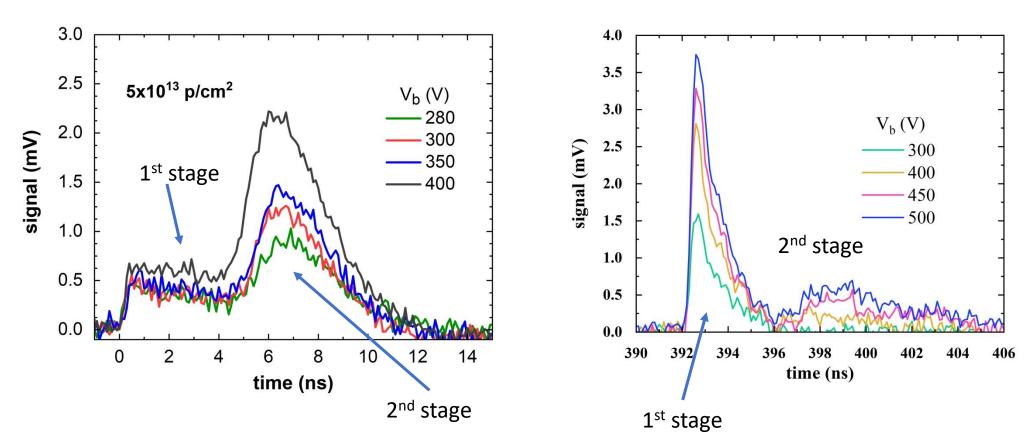
- ◆ Fluence to 1×10¹⁵ -1×10¹⁶ p/cm²
- Beam position monitoring (BPM + Si beam telescopes)
- Current pulse response, TCT, LeCroy WavePro,
 3 GHz bandwidth, 630 nm laser, width 45 ps

Laser illumination of the n^+ contact



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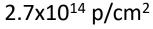
5x10¹³ p/cm²



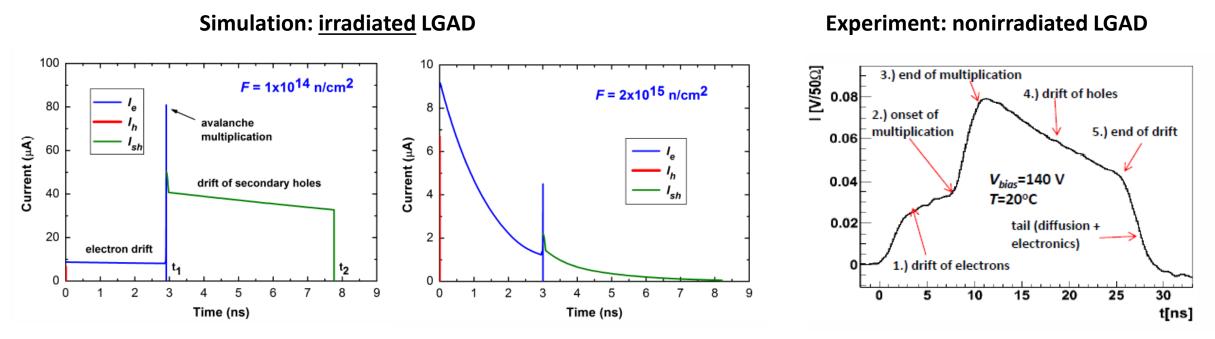
irradiation dose



No reflection as seen at lower F At higher F – details of fine structure



Motivation to consider multistage process with avalanche multiplication



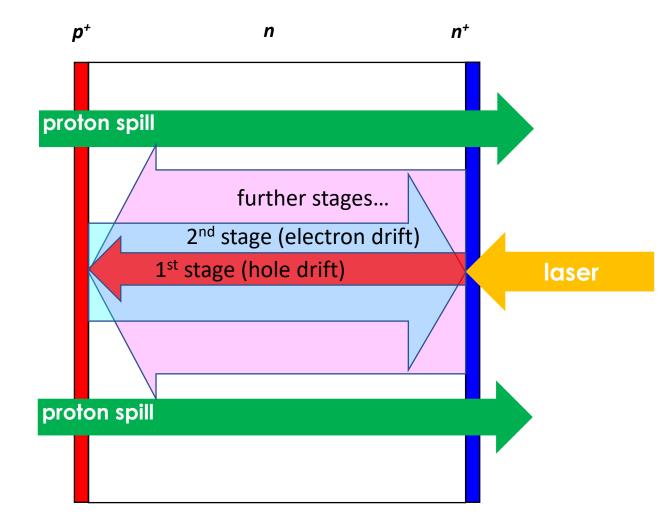
G. Kramberger, et al., 2015 JINST 10 P07006

E. Verbitskaya, et al., 2016 JINST 11 P12012

Charge multiplication in structure without built-in layer

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Multistage process of charge collection



Two stages of drift: 1st stage

- initial hole drift from n⁺ to p⁺
- impact ionization and charge multiplication initiated by holes at p⁺

2nd stage

• electron drift from p⁺ to n⁺

If electric field near n⁺ contact is **high**: electrons initiate multiplication and **3rd stage** of charge collection (hole drift again)

Data treatment and simulations

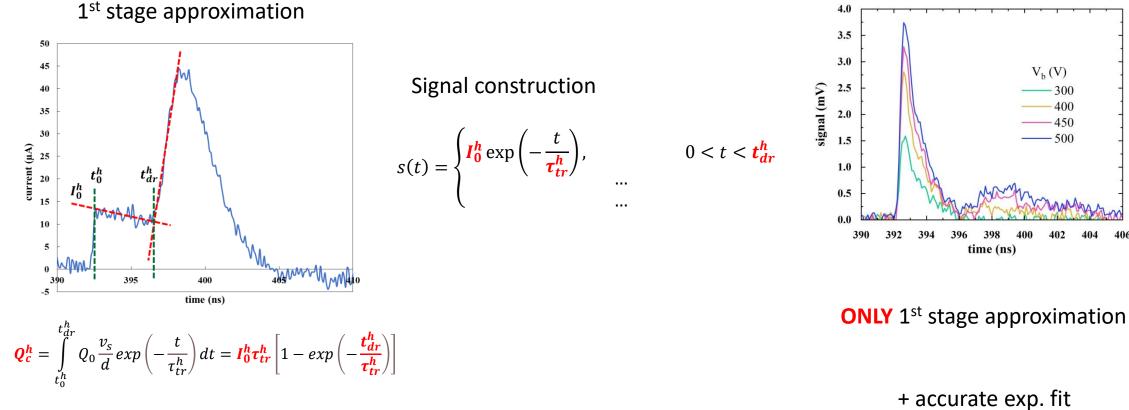
LOWER DOSE: 5×10¹³ p/cm²

HIGHER DOSE: 2.7×10¹⁴ p/cm²

300 400

450

500



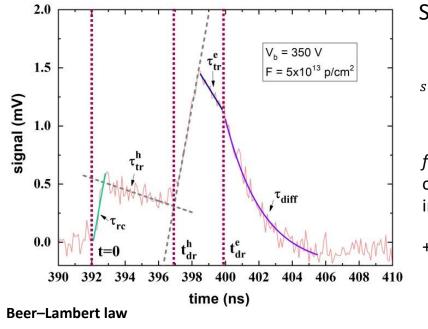
difficult to perform exp. fit

(direct τ_{tr}^h extraction)

Data treatment and simulations

2nd stage and pulse tail

complicated because of carrier cloud size



$$p(x,0) = p_0 e^{-\alpha x}$$

Hole distribution during drift

$$p(x,t) = \frac{1}{2}p_0 \exp\left(\frac{\alpha^2 \sigma^2}{2} - \alpha x\right) \operatorname{erfc}\left(\frac{\alpha \sigma^2 - 2x}{2\sigma}\right)$$
$$\sigma = \sqrt{2Dt}$$

Signal construction

$$s(t) = \begin{cases} I_0^h e^{-\frac{t}{\tau_{tr}^h}}, & 0 < t \le t_{dr}^h \\ s(t = t_{dr}^h) [1 + G_Q f(t)] e^{-\frac{t - t_{dr}^h}{\tau_{tr}^e}}, & t_{dr}^h < t \le t_{dr}^e \\ s(t = t_{dr}^e) e^{-\frac{t - t_{dr}^e}{\tau_{diff}}}, & t > t_{dr}^e \end{cases}$$

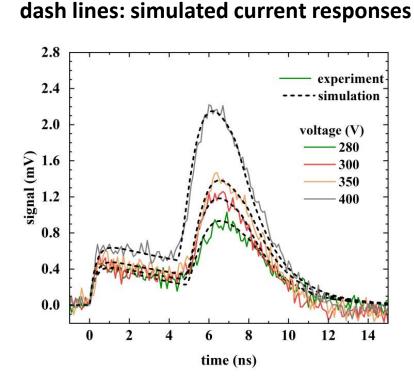
f(t) - the function defined by the change of charge in the detector determined by integration of p(x, t)

+ RC distortion

$$y(t) = \int_0^t s(t')h(t-t')dt'$$

taking into account

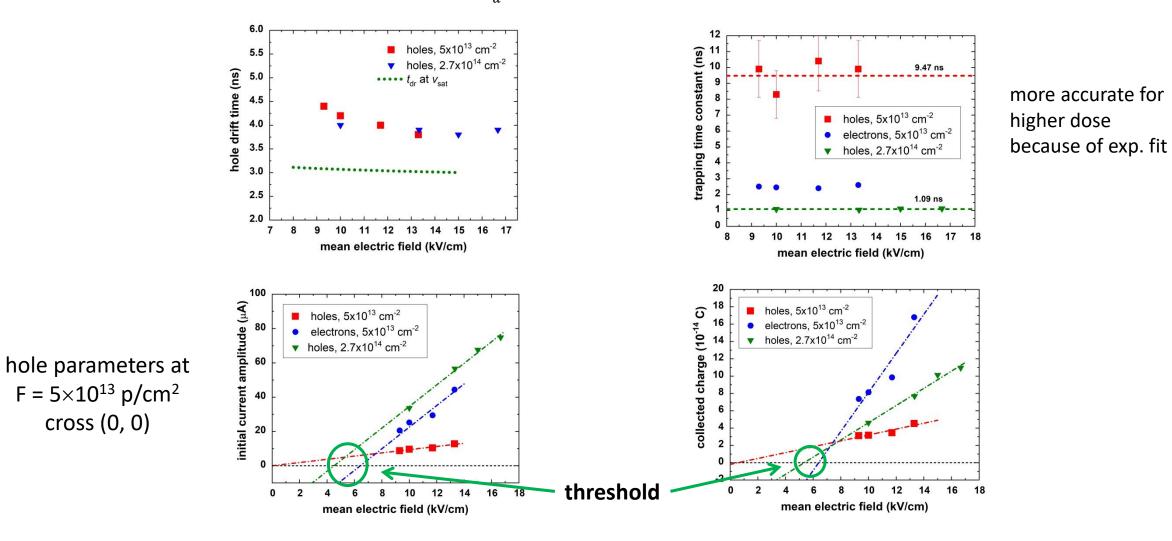
- initial nonuniformity
- diffusion spreading



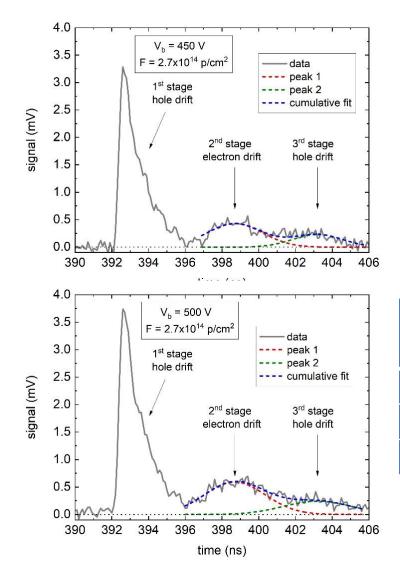
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Carrier transport characteristics

bias voltage \rightarrow mean electric field $\langle E \rangle = \frac{V_b}{d}$



Third stage of charge collection



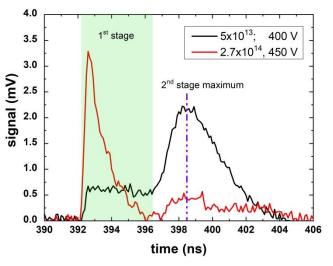
3rd stage is the **drift of holes** after impact ionization produced by electrons near n⁺ contact

Sum of Gaussian fit

$$y(t) = y_0 + \frac{A}{\sigma\sqrt{2\pi}} \exp\left(-\frac{(t-t_m)^2}{2\sigma^2}\right)$$

the result of the fit

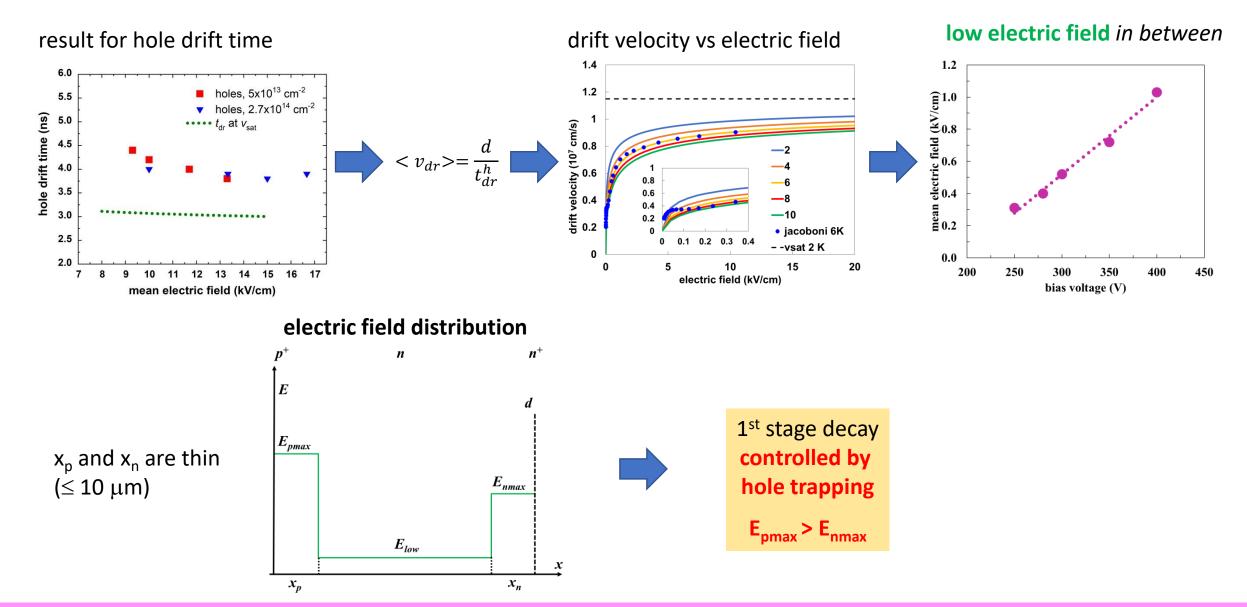
Dose comparison



Parameter	450 V		500 V	
	S2	S 3	S2	S 3
t _m (ns)	398.7	403.2	398.7	403.2
σ (ns)	3.0 ± 0.2	2.9 ± 0.3	3.3 ± 0.1	3.4 ± 0.4
A (10 ⁻¹⁴ C)	3.3 ± 0.2	1.6 ± 0.1	5.0 ± 0.1	2.2 ± 0.2

The time between maxima **correlates** with t_{dr} with drift **velocity below saturated**, but the **current maximum** is determined by **charge** drifting inside the detector

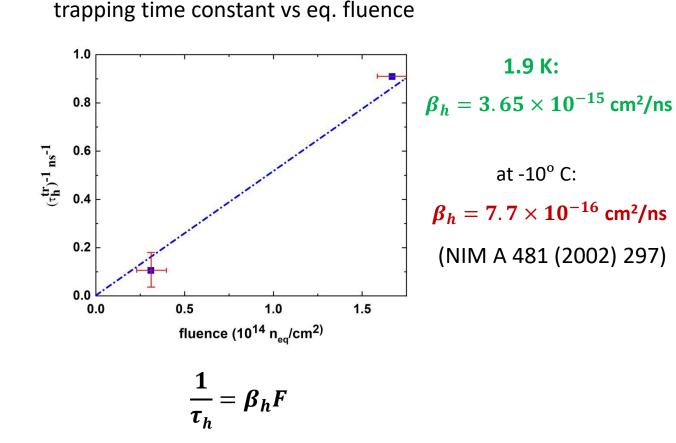
Electric field profile: low field

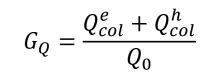


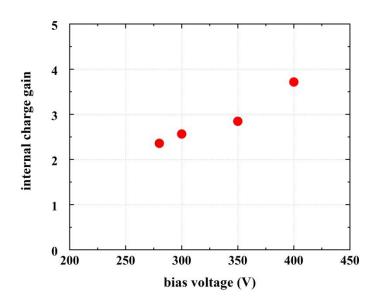
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Internal charge gain and $\tau_{\rm h}$ degradation rate

Internal charge gain







negative feedback due to carrier trapping

Conclusions

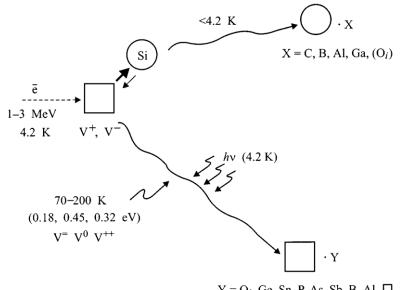
- In the unique experiment at 1.9 K, Si p⁺/n/n⁺ detector maintains operation as a regular diode structure with highly doped contacts.
- The effect of sequential stages of charge multiplication was found. The third stage of charge collection was observed.
- The developed procedure of TCT data treatment for irradiated Si detectors with avalanche multiplication allowed extraction of full set of carrier transport parameters and internal charge gain.
- Comparison of the trapping time constant degradation rate at 1.9 K and room temperature showed fivefold increase of β_h at 1.9 K.

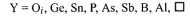
New questions have arisen:

- conservation of the low-field region after polarization,
- ✤ relaxation of current response after spill escape.

Thank you for your attention!

Why $E_{pmax} > E_{nmax}$?





J.D. Watkins

At such a low temperature defect formation is not a well-known mechanism There is J.D. Watkins hypothesis that mobility of initial defects is different and at T < 4.2 K more donors (hole traps) are forming, while at a RT more acceptors (electron traps) are forming.